

	Hit s	Search Text	DBs
18	0	((selective\$5 or response or signal\$4 or (defect near9 portion)) same (sensor or detector or interferometer or microscope or SEM) same (mitigat\$4 or reduc\$4 or decreas\$4 or monitor\$4 or reflow or (thermal near5 reflow) or RELACS or SAFIER or post\$4heat\$4 or heat\$4) same (line\$3dege\$3roughness or ((edge or side\$4) near12 roughnes\$4) or LER or (line\$3 near3 edge near4 roughnes\$3)) same (pattern or ((resist or photoresist) near9 (structure or pattern\$4)))) and (((trim\$4 near5 etch\$4) or trim\$5 or etch\$5) same (CD or (critical near5 dimension)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
19	1	((selective\$5 or response or signal\$4 or (defect near9 portion)) same (sensor or detector or interferometer or microscope or SEM) same (mitigat\$4 or reduc\$4 or decreas\$4 or monitor\$4 or reflow or (thermal near5 reflow) or RELACS or SAFIER or post\$4heat\$4 or heat\$4) same (line\$3dege\$3roughness or ((edge or side\$4) near12 roughnes\$4) or LER or (line\$3 near3 edge near4 roughnes\$3)) same (pattern or ((resist or photoresist) near9 (structure or pattern\$4))))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
20	38	S21 NOT S20	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB

	Hit s	Search Text	DBs
21	43	((sensor or detector or interferometer or microscope or SEM) same (detect\$4 or monitor\$4 or respons\$4 or sens\$5 or observ\$5) same (line\$4edge\$4roughness or ((edge or side\$4) near12 roughnes\$4) or LER or (line\$3 near3 edge near4 roughnes\$3)) same (pattern or ((resist or photoresist) near9 (structure or pattern\$4)))) and ((mitigat\$4 or reduc\$4 or decreas\$4 or chang\$4 or alter\$4 or correct\$4) same (line\$4edge\$4roughness or ((edge or side\$4) near12 roughnes\$4) or LER or (line\$3 near3 edge near4 roughnes\$3)) same ((pattern or structure) near12 (resist or photoresist)))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB
22	13	((sensor or detector or interferometer or microscope or SEM) same (mitigat\$4 or reduc\$4 or decreas\$4 or chang\$4 or alter\$4 or correct\$4) same (detect\$4 or monitor\$4 or respons\$4 or sens\$5) same (line\$4edge\$4roughness or ((edge or side\$4) near12 roughnes\$4) or LER or (line\$3 near3 edge near4 roughnes\$3)) same (pattern or ((resist or photoresist) near9 (structure or pattern\$4))))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB

	Hit s	Search Text	DBs
23	1	((sensor or detector or interferometer or microscope or SEM) same (detect\$4 or monitor\$4 or respons\$4 or sens\$5 or observ\$5) same (line\$4edge\$4roughness or ((edge or side\$4) near12 roughnes\$4) or LER or (line\$3 near3 edge near4 roughnes\$3)) same (pattern or ((resist or photoresist) near9 (structure or pattern\$4)))) and ((mitigat\$4 or reduc\$4 or decreas\$4 or chang\$4 or alter\$4 or correct\$4) near12 (line\$4edge\$4roughness or ((edge or side\$4) near12 roughnes\$4) or LER or (line\$3 near3 edge near4 roughnes\$3)) near16 ((defect near9 portion) or select\$5 or portion) near22 ((pattern or structure) near12 (resist or photoresist)))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB

	Hit s	Search Text	DBs
25	30	((sensor or detector or interferometer or microscope or SEM) same (detect\$4 or monitor\$4 or respons\$4 or sens\$5 or observ\$5) same (line\$4edge\$4roughness or ((edge or side\$4) near12 roughnes\$4) or LER or (line\$3 near3 edge near4 roughnes\$3)) same (pattern or ((resist or photoresist) near9 (structure or pattern\$4)))) and ((mitigat\$4 or reduc\$4 or decreas\$4 or chang\$4 or alter\$4 or correct\$4 or smooth\$6) near12 (line\$4edge\$4roughness or ((edge or side\$6) near12 roughnes\$4) or LER or (line\$3 near3 edge near4 roughnes\$3)) near22 ((pattern or structure) near12 (resist or photoresist)))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB